



AF / IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:	§	Attorney Docket No. 24061.49
Chih-Wei Hsu	§	(2003-0125)
	§	
Serial No.: 10/791,930	§	Customer No. 42717
	§	
Filed: March 3, 2004	§	Group Art Unit: 2125
	§	
For: SYSTEM AND METHOD FOR	§	Examiner: Kosowski, Alexander J.
PROCESS CONTAMINATION	§	
PREVENTION FOR SEMICONDUCTOR	§	
MANUFACTURING	§	

**RESPONSE**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action mailed September 19, 2005, please reconsider the application in light of the following amendments and remarks:

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 8 of this paper.